



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q84452

Michel PUECH

Appln. No.: 10/516,455

Group Art Unit: 1763

Confirmation No.: 2876

Examiner: Allan OLSEN

Filed: December 3, 2004

For: METHOD AND DEVICE FOR SUBSTRATE ETCHING WITH VERY HIGH POWER  
INDUCTIVELY COUPLED PLASMA

**AMENDMENT UNDER 37 C.F.R. § 1.111**

**MAIL STOP AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated March 28, 2006, please amend the above-identified application as follows on the accompanying pages.

**TABLE OF CONTENTS**

AMENDMENTS TO THE CLAIMS.....2

REMARKS.....7